

Barriers associated with trace organics and discoveries on how to reuse semiconductor Fab wastewater for ultrapure make-up water

Paul Westerhoff, PhD, PE

Regents Professor & Fulton Chair of Environmental Engineering

Dr. Junli Wang (Post-doctoral scholar)

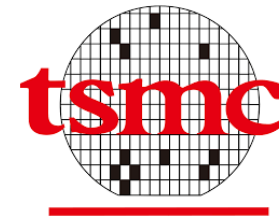
Hyunki “Arnold” Jung (PhD student)

School of Sustainable Engineering & The Built Environment

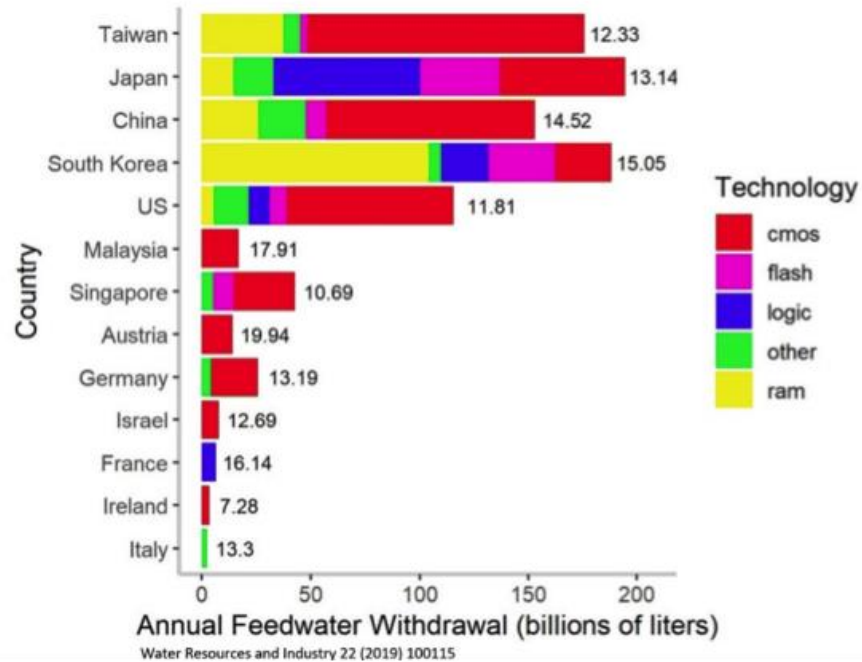
Ira A. Fulton Schools of Engineering

Arizona State University (Tempe, Arizona USA)

Prof. Xin Yang Group (Sun Yat-Sen University)



Water used by fabs



Fabs use a LOT of water (~1000 L per 12" wafer)

A typical Fab uses as much water as 50,000 to 100,000 homes per year

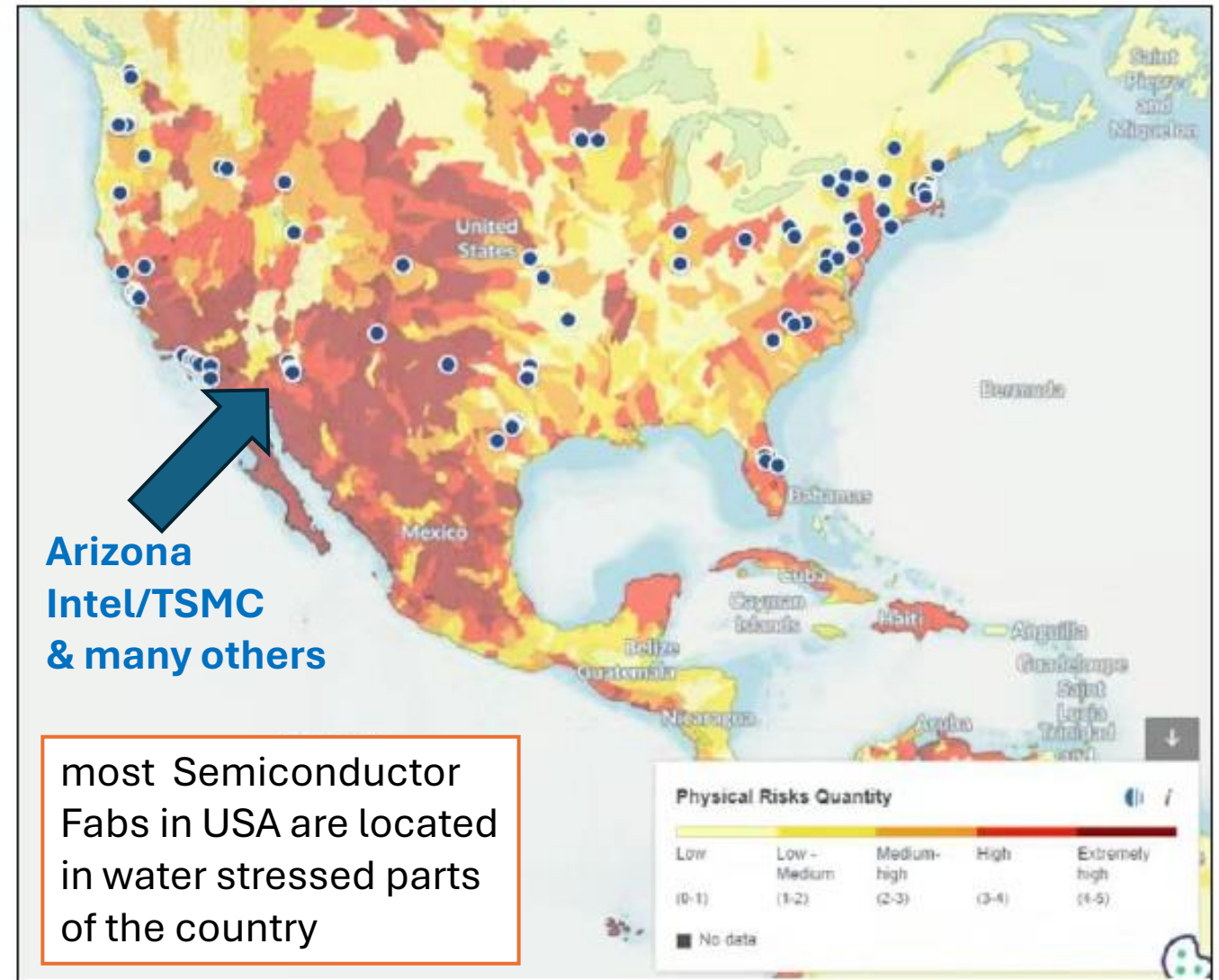


Figure 1: Overlay of U.S.-based chip fab locations (SIA, 2023) on the physical water risks quantity map maintained by the World Resources Institute (www.wri.org/aqueduct).

John H. Rydzewski (WEFTEC, 2024)

Typical Fab Wastewater Treatment Train *with Zero Liquid Discharge (ZLD)*

**Fab
Processes**



Peroxide
Quenching



**Solid
Waste**



Biological
treatment
for
solvents &
ammonia



Reverse
osmosis

Brine



Chemical
Softening
& Ion
Exchange



What is process for Salt Crystallization in Industrial Wastewater



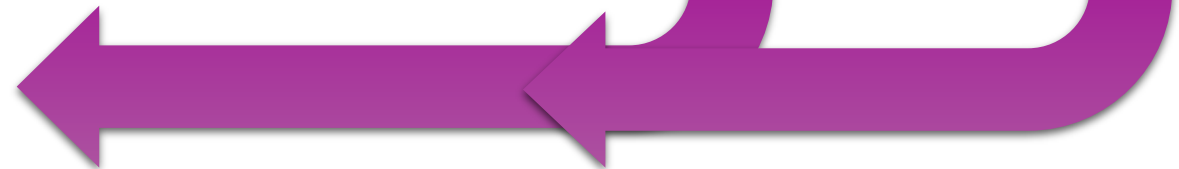
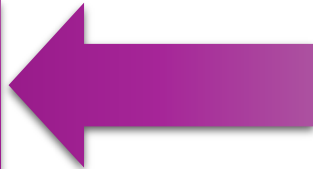
**Solid
Waste**



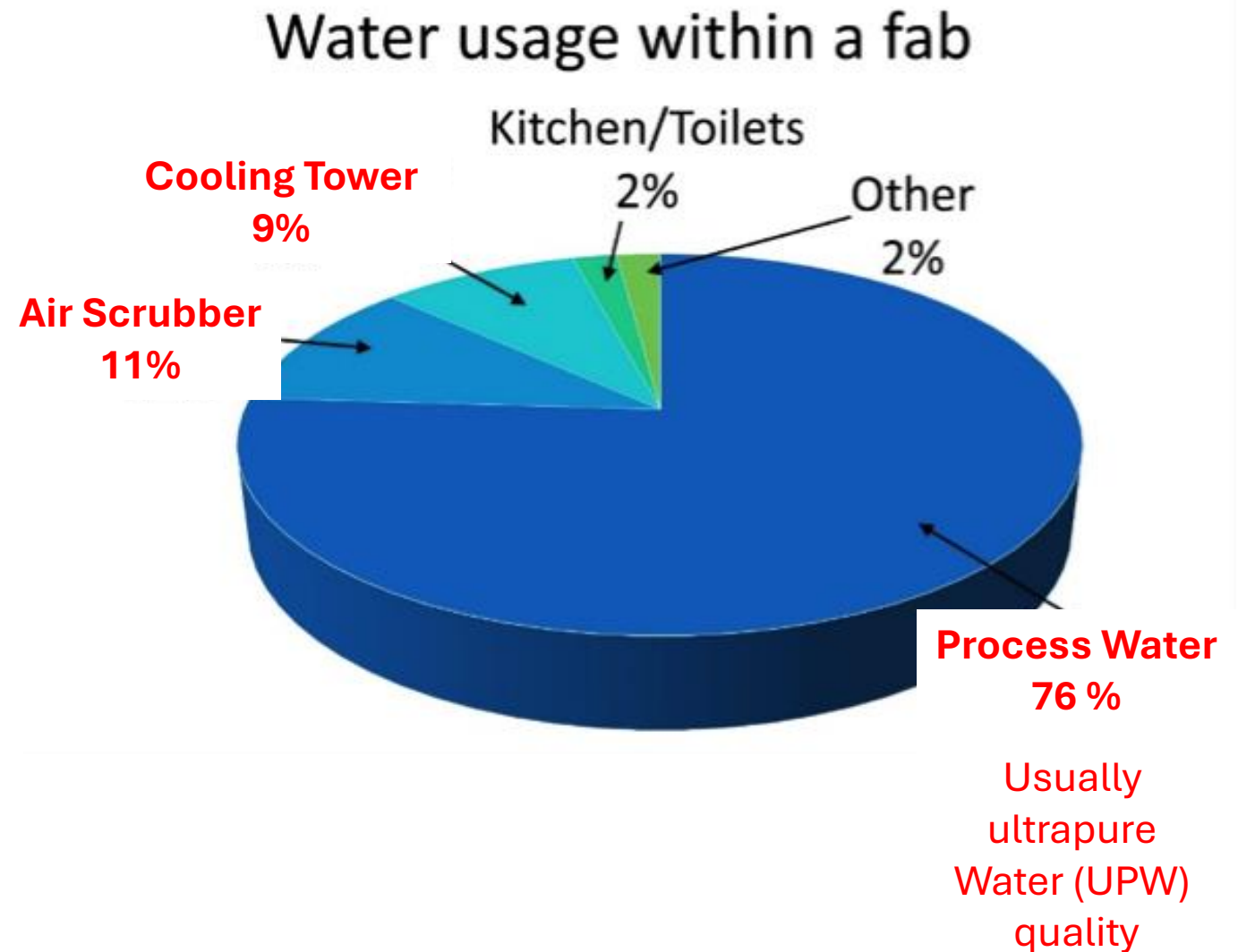
Distillation
&
Crystallization

For cooling Towers
& Scrubbers

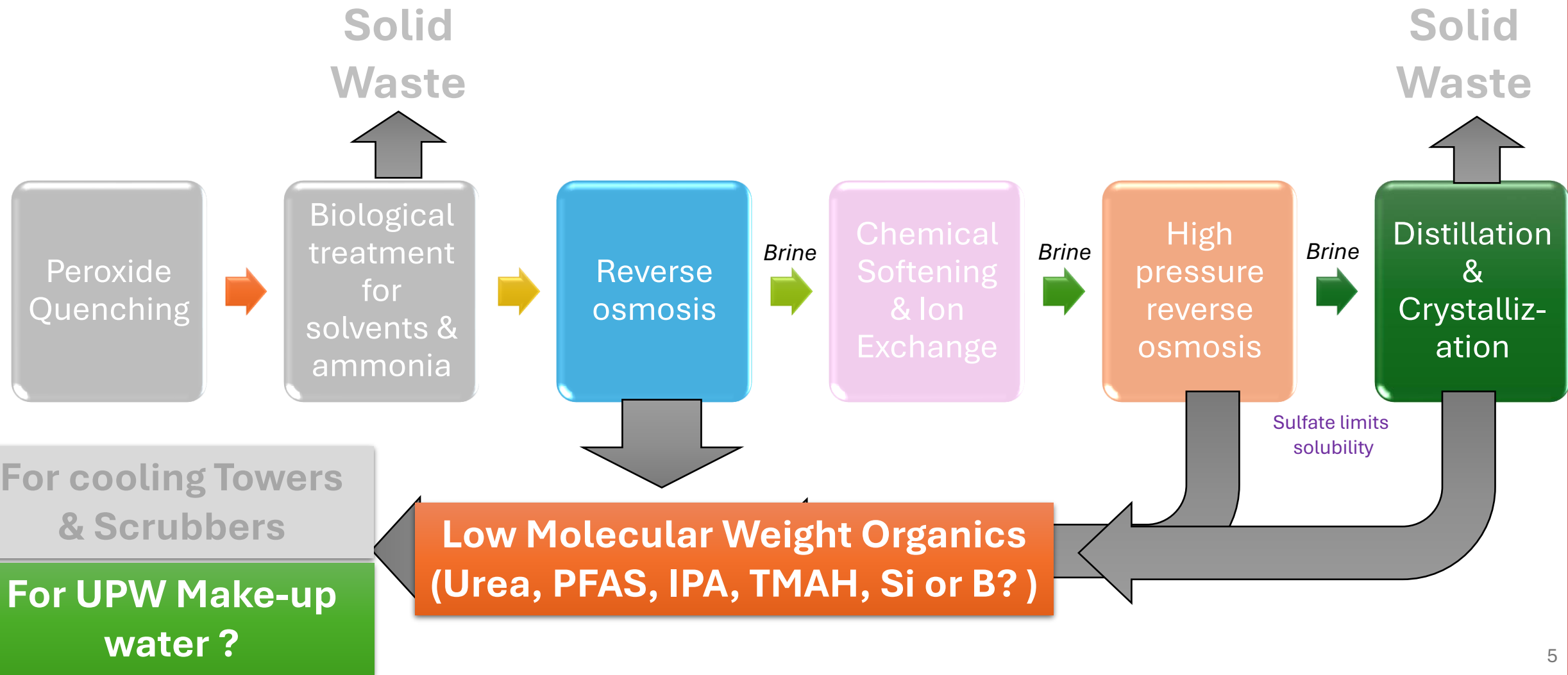
**Clean
water**



Simply not
enough “reuse”
water demand
without reusing
water in Fab for
process make-
up water



Challenges to Reusing Industrial Wastewater



Research Need

- Develop treatment processes to effectively **destroy urea and other compounds present in RO permeate** from Fab wastewater
- Use this treated water as UPW make-up water

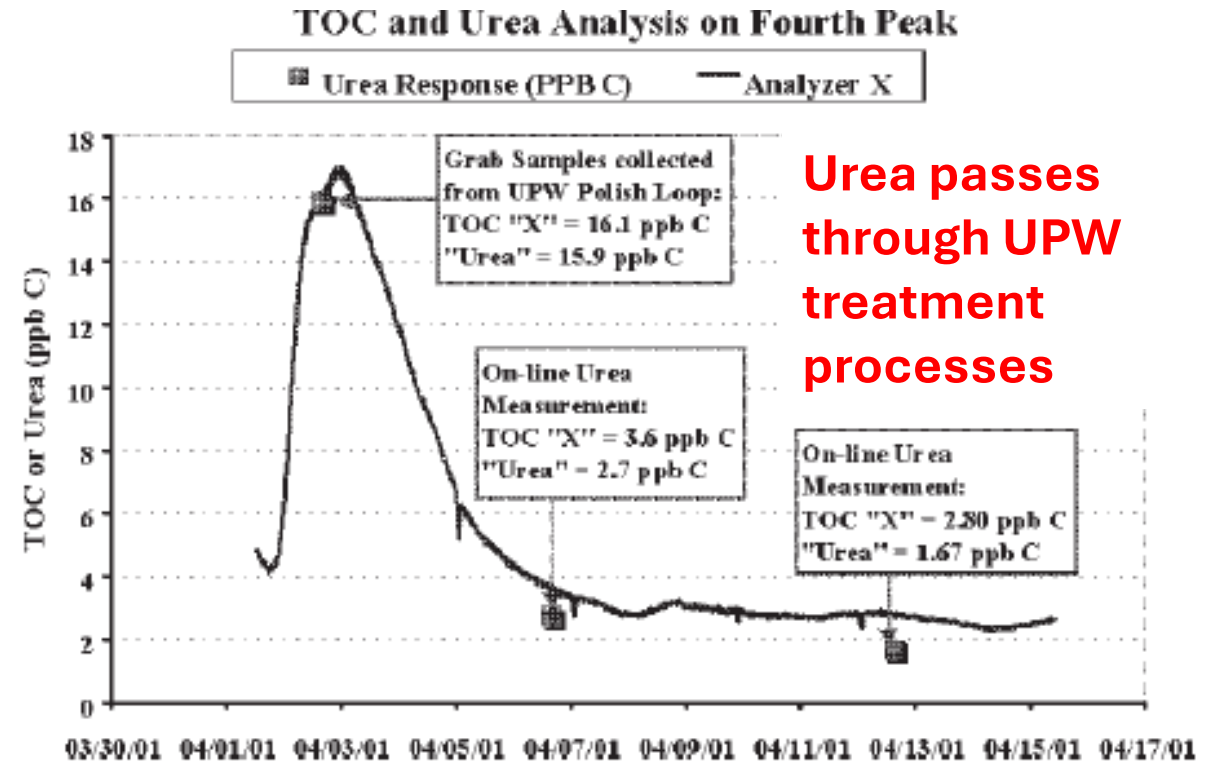


Figure 5. Plot showing correlation between the measured urea concentration and the TOC concentration measured by Analyzer X during the fourth excursion.

Approach

X^* can be produced by UV Light, Ozone or other processes

But which X^* should we produce ?

Urea
or other
Low molecular
Weight organic
Compounds

+

**Reactive
Radical
Species
(X^*)**

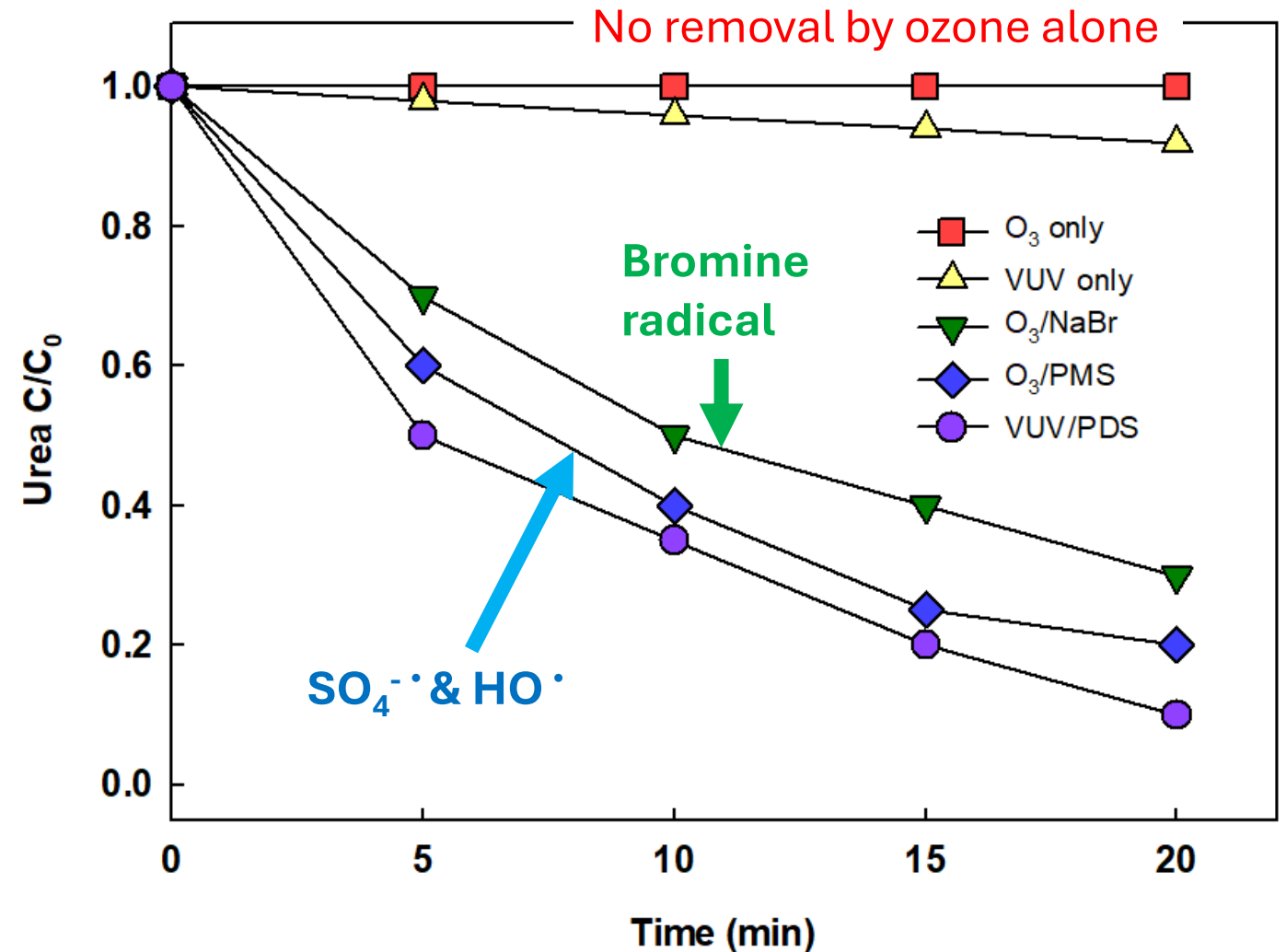


CO₂ & ions
easily removed
by UPW
processes

	O ₃	•OH	SO ₄ ^{•-}	e ⁻ _(aq)	H•	O ⁻	Br•	Br ₂ ^{•-}	HBrO	Cl ₂ ^{•-}	CO ₃ ^{•-}
Urea	5×10 ⁻²	7.9×10 ⁵	-	3×10 ⁵	< 3×10 ⁴	-	-	-	-	-	1×10 ³
Tetramethylamm onium hydroxide (TMAH)	-	7.5×10 ⁷	9×10 ⁴	-	-	1.2×10 ⁸	-	-	-	< 1×10 ³	-
Acetone	3.2×10 ⁻²	1.1×10 ⁸	-	6.5×10 ⁹	2.6×10 ⁶	-	-	-	-	1.4×10 ³	1.6×10 ²
Isopropanol (IPA)	1.9	7.5×10 ⁹	5.3×10 ⁷	-	7.4×10 ⁷	1.2×10 ⁹	-	-	-	1.5×10 ⁵	4.3×10 ⁴
Dimethyl sulfoxide (DMSO)	8.1	6.6×10 ⁹	-	2.4×10 ⁶	6.2×10 ⁶	-	-	-	-	-	-

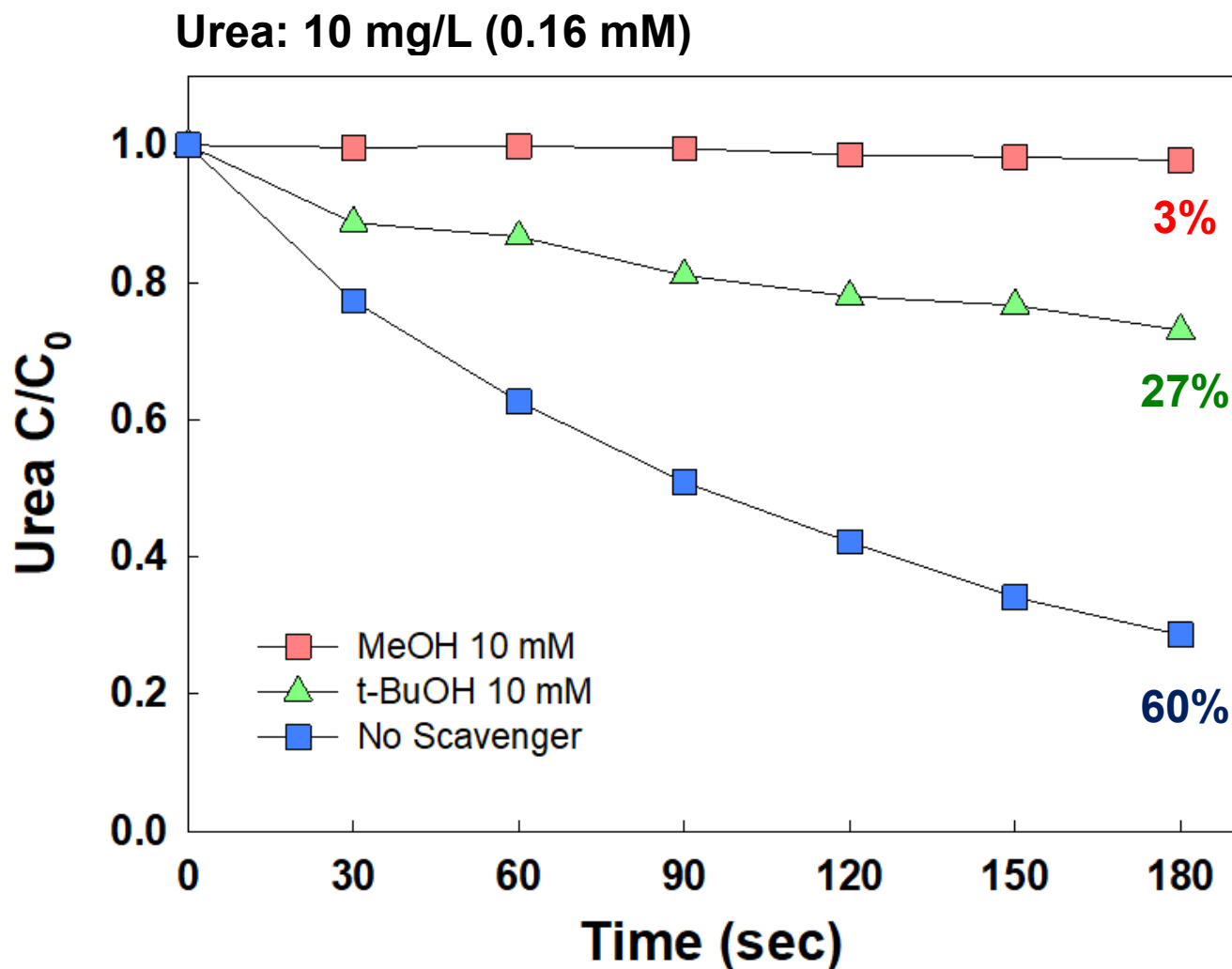
Approach #1 – Ozone + Bromide or Peroxymonosulfate (PMS)

Produces bromine radical ($\text{Br}^\bullet$), sulfate radical ($\text{SO}_4^{\bullet-}$) or hydroxyl radical ($\text{HO}^\bullet$)



Approach #1 – Ozone + Peroxymonosulfate (PMS)

Differentiating mechanisms



MeOH: Quench HO• and SO₄•⁻

t-BuOH: Quench only HO•

$k_{\text{HO}\cdot}$ **$7.9 \times 10^5 \text{ M}^{-1} \text{ s}^{-1}$**
(from literature)

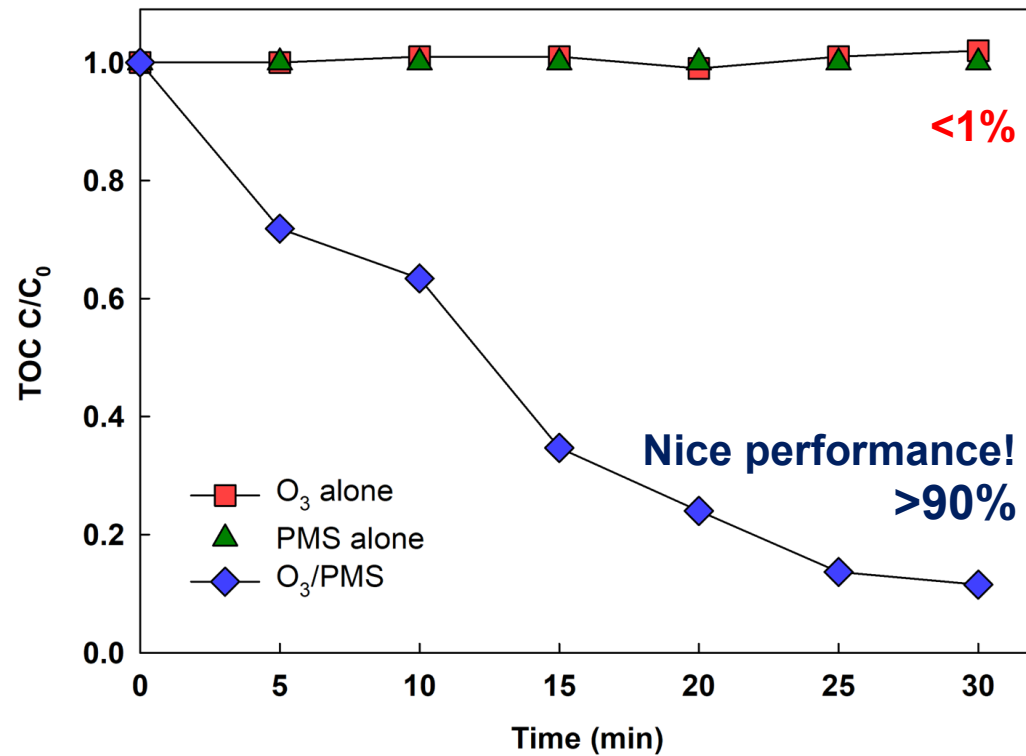
$k_{\text{SO}_4\cdot\text{--}, \text{urea}}$: **$4.01 \times 10^7 \text{ M}^{-1} \text{ s}^{-1}$**

from Xin Yang Group (Sun Yat-Sen University)

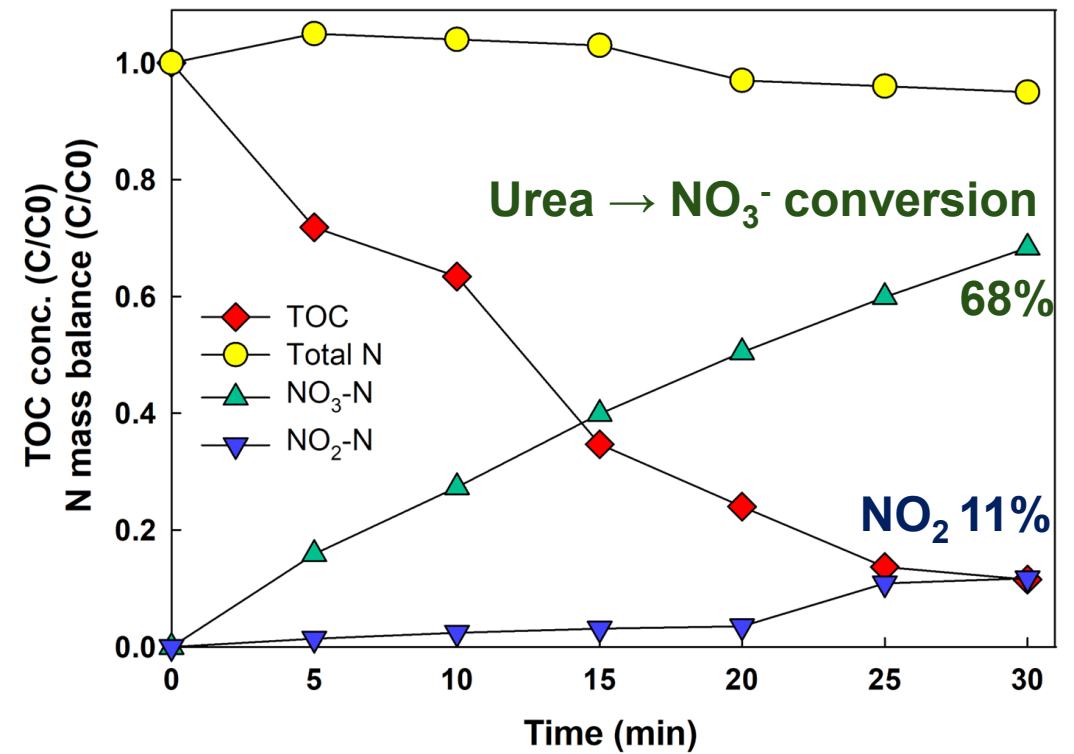
By-Products of Urea oxidation

TOC = Total organic carbon

TOC removal (Co = urea 10 ppm)

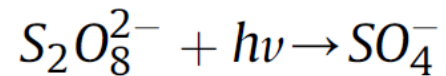


Nitrogen mass balance



Approach #2 – Vacuum Ultraviolet Light + Peroxydisulfate (PDS)

Produces sulfate radical ($\text{SO}_4^{\cdot-}$) + 185nm/254 nm light



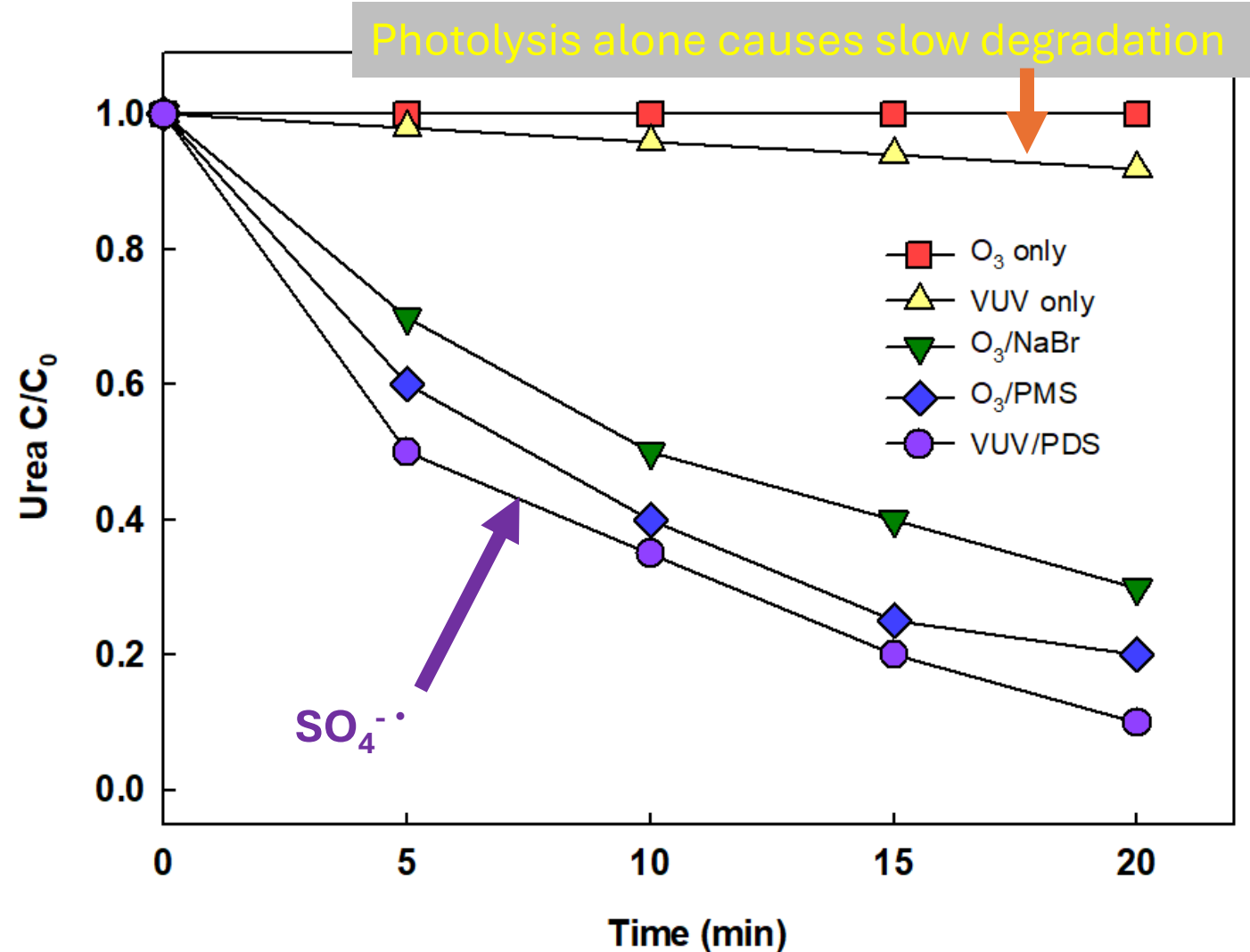
VUV/UV/PDS technology:

Volume = 2.65 L

46 W lamp: 185/254nm

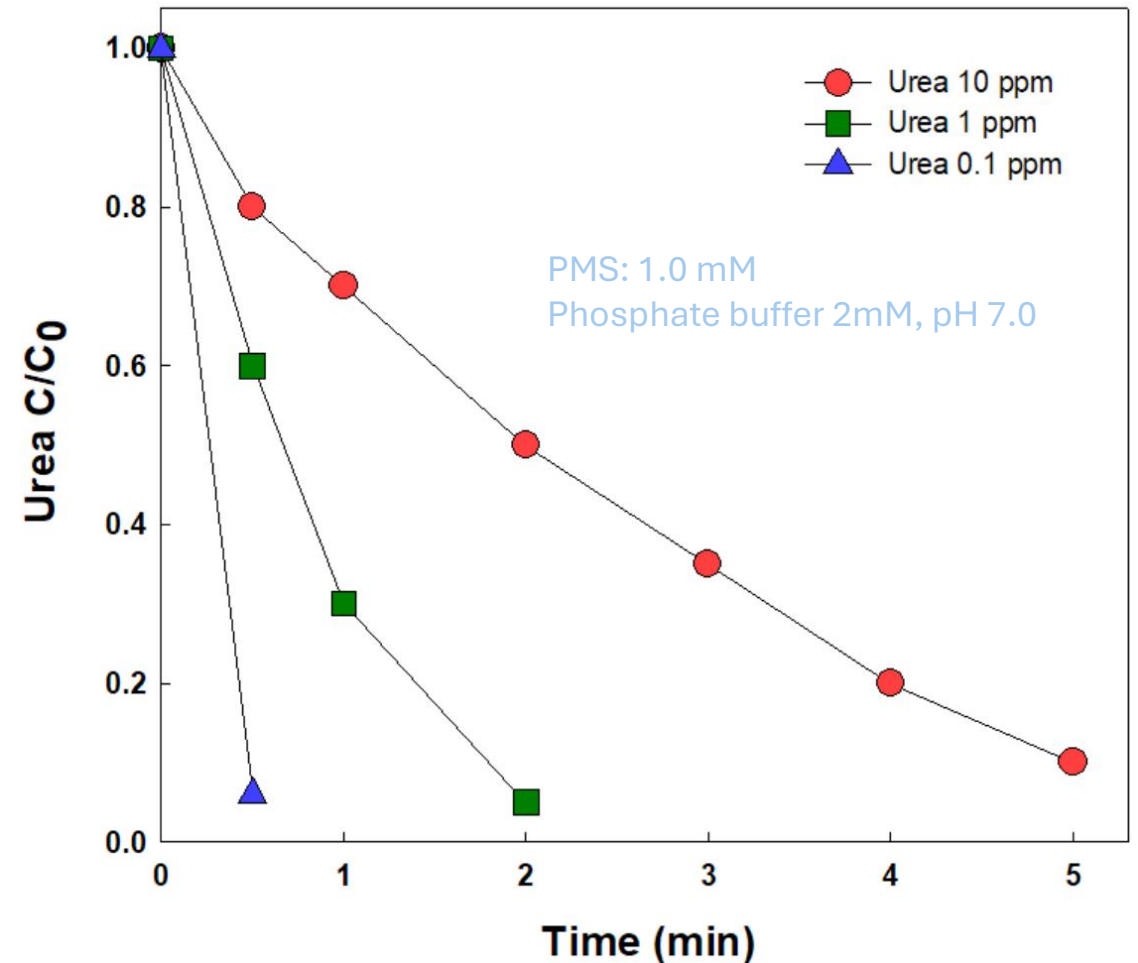
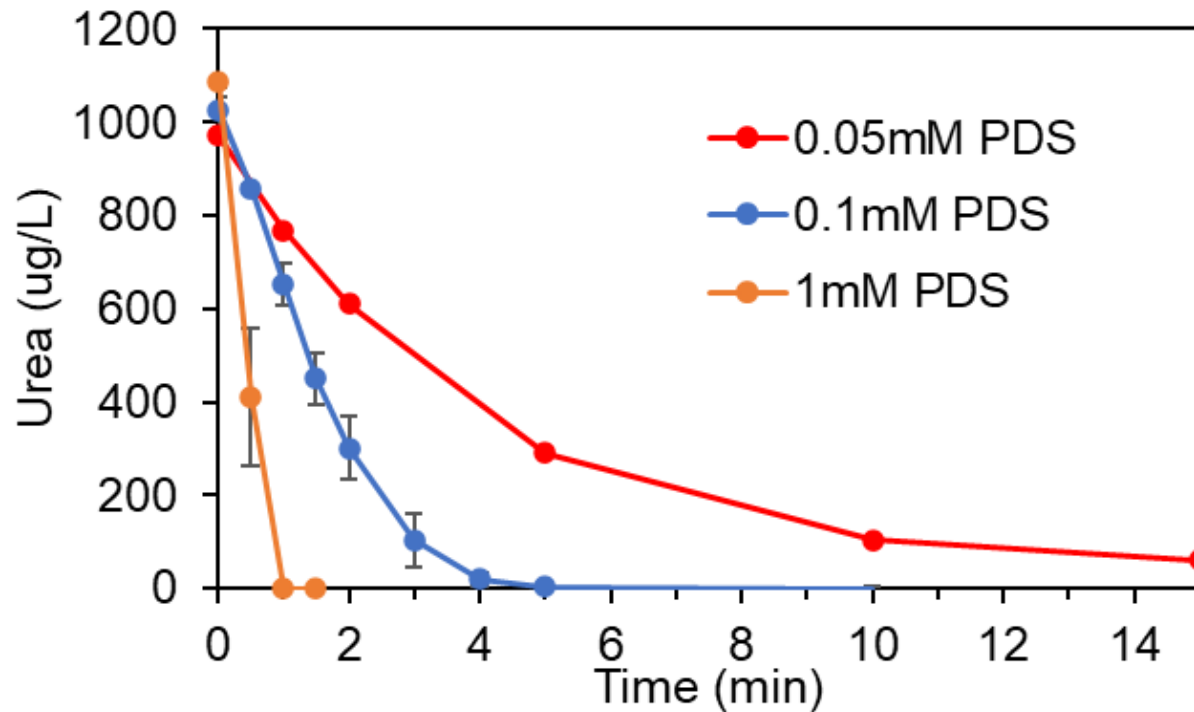
Spike PDS, 23.8-238 mg/L $\text{Na}_2\text{S}_2\text{O}_8$

Urea: 1-60 mg/L

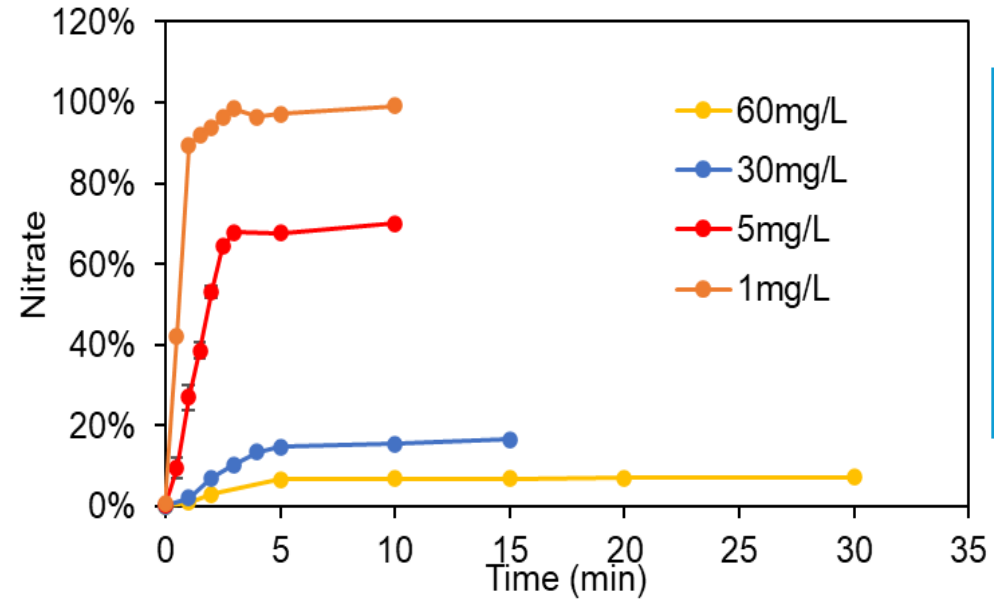
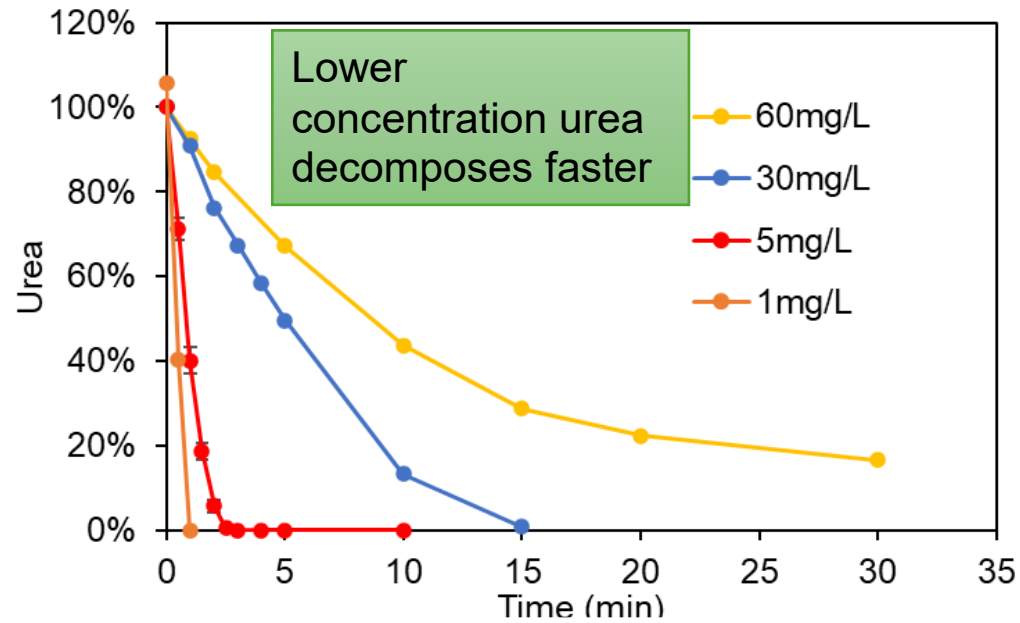


Effects of initial PDS or Urea Concentrations

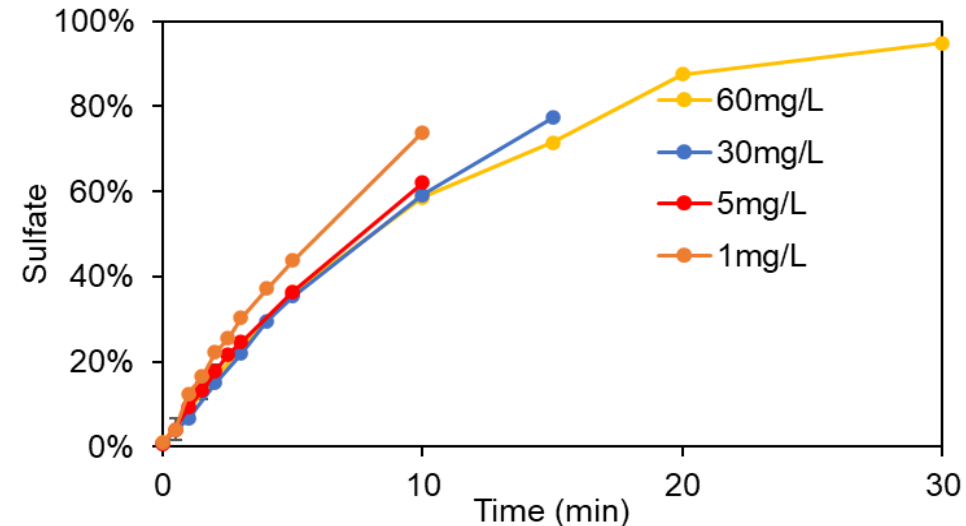
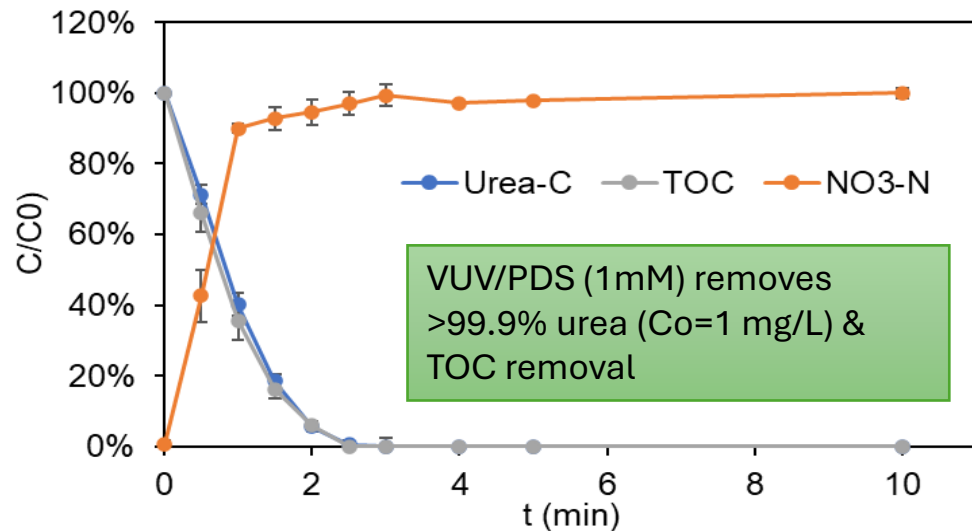
Each influences steady state $SO_4^{\cdot -}$ concentrations



By-products of urea reactions with VUV/PDS (1 mM)



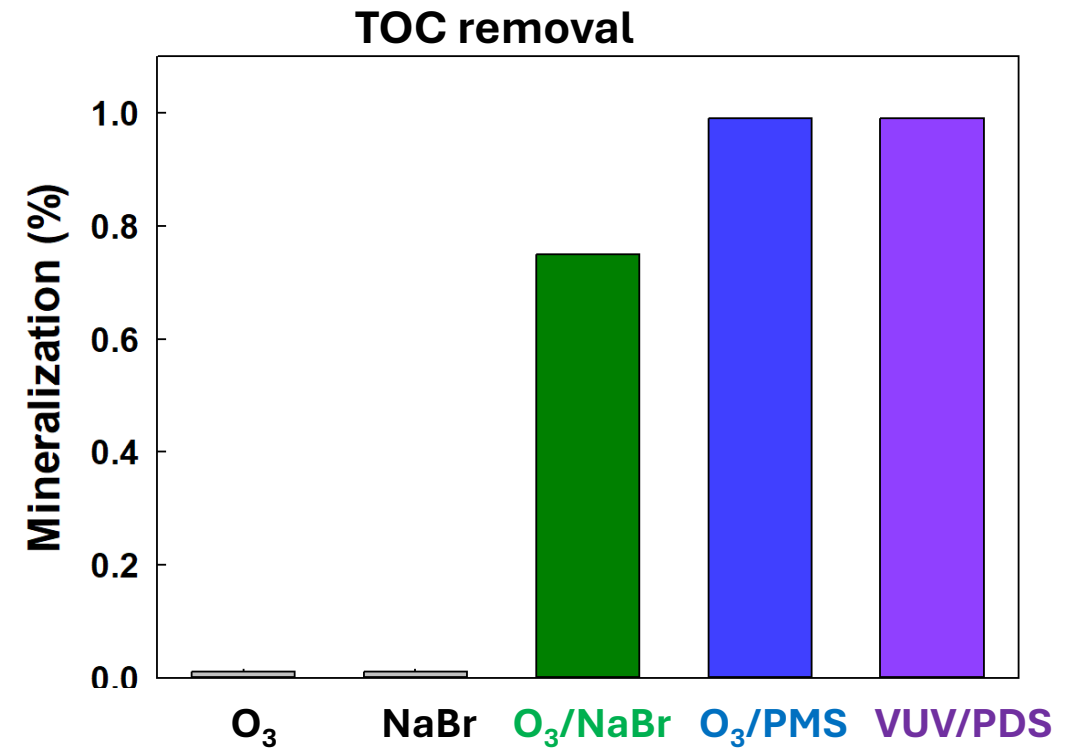
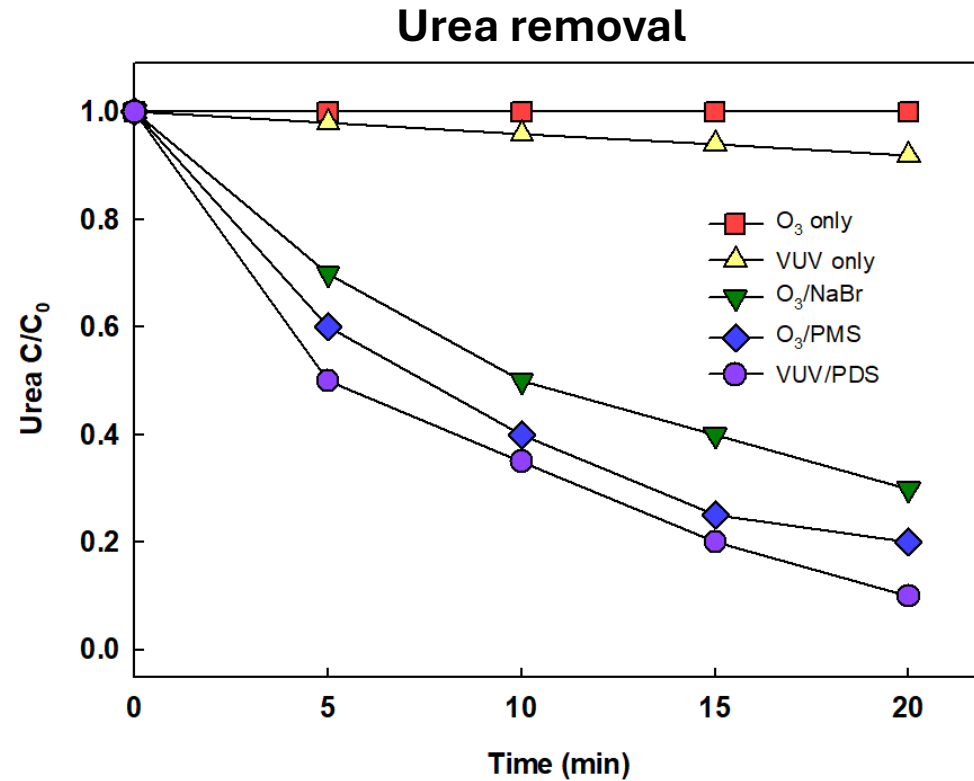
Nitrate formation:
Mechanisms change at higher initial Urea concentrations



Not all PDS are converted into sulfate. There are PDS left in the solution.

Comparing Degradation & ByProducts

VUV/PDS emerges as better potential candidate to destroy Urea

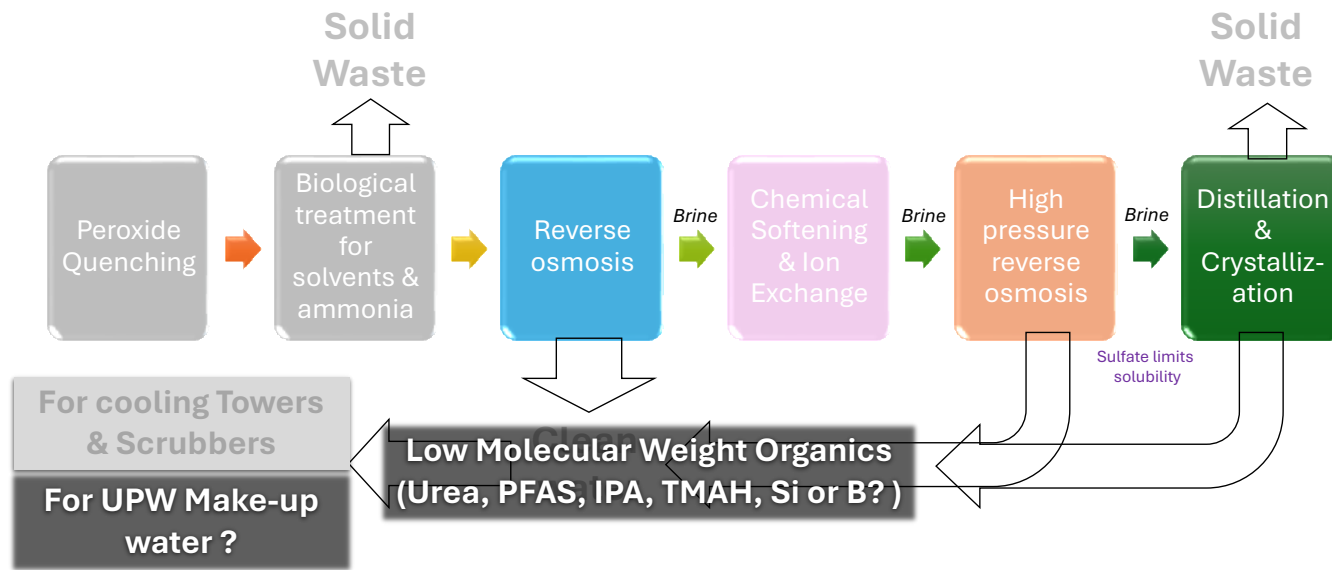


Broader perspective around capabilities of Radical Species to oxidize target LMW Organics

	O ₃	•OH	SO ₄ ^{•-}	e ⁻ _(aq)	H•	O ^{•-}	Br•	Br ₂ ^{•-}	Cl•	Cl ₂ ^{•-}	CO ₃ ^{•-}
Urea	5×10 ⁻²	7.9×10 ⁵	4.0×10 ⁷	3×10 ⁵	< 3×10 ⁴	-	1.3×10 ⁷	BDL	-	-	1×10 ³
Tetramethylammonium hydroxide (TMAH)	-	7.5×10 ⁷	9×10 ⁴	-	-	1.2×10 ⁸	6.6×10 ⁶	BDL	-	< 1×10 ³	-
Acetone	3.2×10 ⁻²	1.1×10 ⁸	<10 ⁶	6.5×10 ⁹	2.6×10 ⁶	-	5.2×10 ⁷	BDL	1.1 ×10 ⁸	1.4×10 ³	1.6×10 ²
Isopropanol (IPA)	1.9	7.5×10 ⁹	5.3×10 ⁷ 7.1×10 ⁷	-	7.4×10 ⁷	1.2×10 ⁹	2.6×10 ⁷	BDL	1.1 ×10 ⁹	1.5×10 ⁵	4.3×10 ⁴
Dimethyl sulfoxide (DMSO)	8.1	6.6×10 ⁹	2.0×10 ⁹	2.4×10 ⁶	6.2×10 ⁶	-	5.8×10 ⁷	BDL	1.8 ×10 ⁹	3.1 ×10 ⁶	-

Red values provided by collaborator: Xin Yang Group (Sun Yat-Sen University)

Conclusions



- **Sulfate radical** generated by **VUV/PDS** (faster) or **O₃/PMS** can mineralize urea and other low molecular weight organics present in reverse osmosis permeates of Fab wastewaters
- **Byproducts of this process** (nitrate, sulfate) are at lower concentrations than present in municipal tap water - and therefore **readily removed by existing UPW treatment systems**
- **Pilot testing** of process + UPW system will start late 2025

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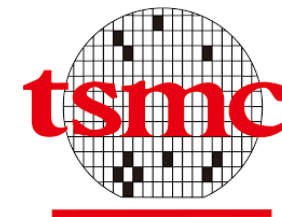
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Effect of solution pH

PMS is acidic when added to RO permeate water

